

## **Semiconductor wafer handler**

### ABSTRACT OF THE INVENTION

5        A semiconductor wafer handler comprises a ring (70)  
attached to a hub (80) by a plurality of spokes (90). Vacuum is  
applied to the surface of the semiconductor wafer through  
orifices (100) containing in the ring (70). Water and/or  
nitrogen can be applied to the surface of the semiconductor  
10 wafer through orifices (110) contained in the spokes (90).